

## **w**kulite

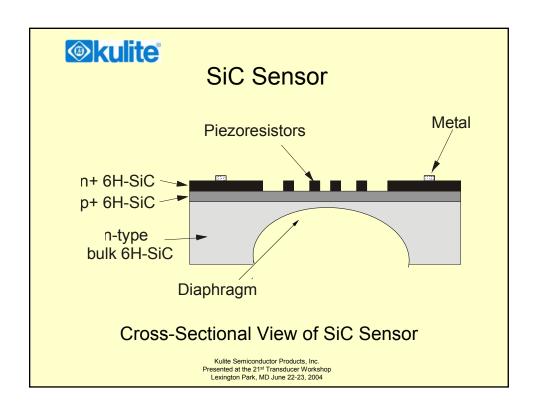
## Sensing Requirements

- High Temperatures
- High Vibration
- Typically 25 psi Up To Few Thousand psi
- Static and Dynamic

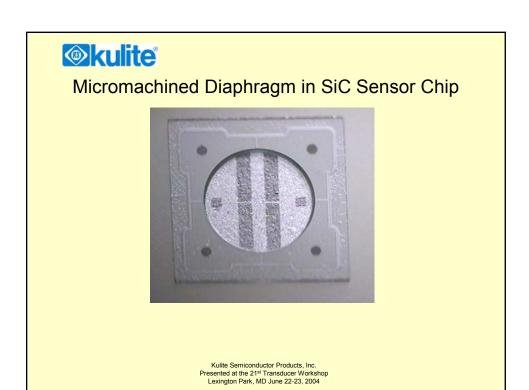
## SiC Piezoresistive Sensors

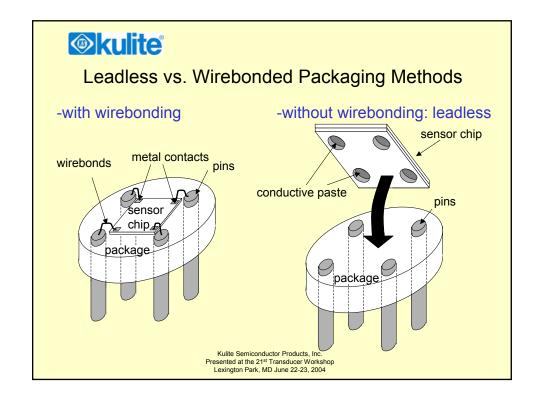
- Expected To Replace Si For Γ>700°C
- All SiC Design
- Leadless Packaging Approach

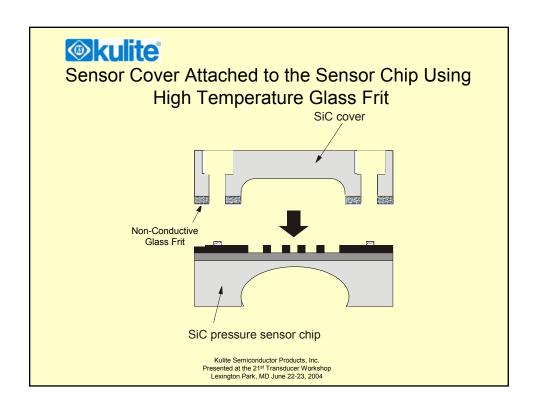
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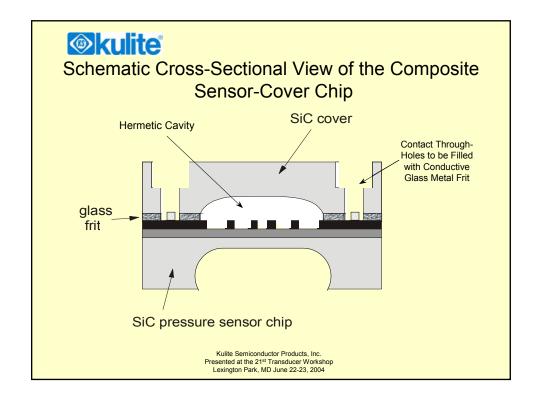


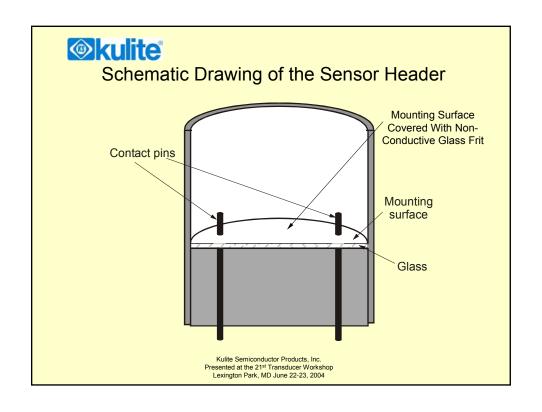


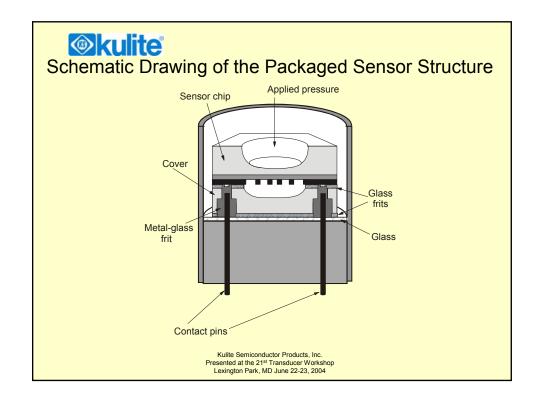


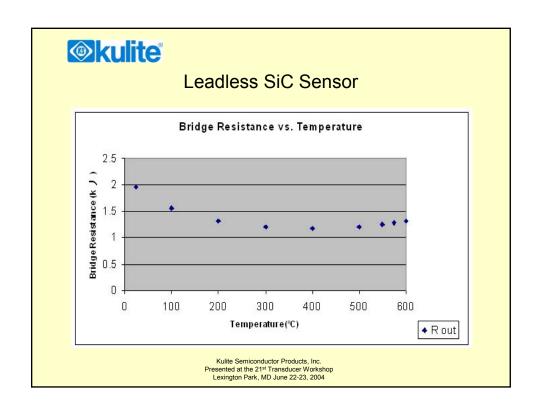


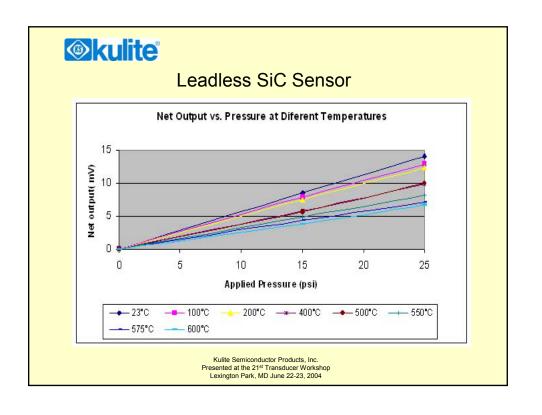














## Summary

- · SiC vs. Si
- Low and High Pressure SiC Sensors Fabricated and Packaged
- 25-1000 psi Sensor Performance up to 600°C Demonstrated
- Sensor Performance Consistent With Previously Reported Data
- Low Pressure Sensing Thin SiC Diaphragm
  - Finite Element Analysis
- · Sensor Optimization
  - ➤ Leadless SiC Sensor Chip
  - ➤ Leadless Assembly

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